

**ABSTRACT OF THE DISCLOSURE**

There is provided a service method, a service system, and a manufacturing/inspection apparatus that can reduce the initial cost of use of the apparatus at the time of introducing a manufacturing/inspection apparatus and maintain the accuracy after introduction of the apparatus. In the service method for using the manufacturing/inspection apparatus for manufacturing or inspecting products such as semiconductor wafer, semiconductor device, exposure mask or liquid crystal device, the charge for use of the manufacturing/inspection apparatus is set based on the manufacturing or inspection difficulty information of the product manufactured or inspected with the manufacturing/inspection apparatus and the running information of the manufacturing/inspection apparatus stored in a physical memory medium.